

Japan TC Chapter of Information and Control Global Technical Committee Meeting Summary and Minutes

Japan Standards Spring 2015 Meetings
Thursday, April 23, 2015, 1:30 p.m. - 5:30 p.m.
SEMI Japan office, Tokyo, Japan

Next Committee Meeting

Tuesday, June 30, 2015, 1:30 p.m. – 5:00 p.m. <Japan Time>
Japan Standards Summer 2015 Meetings, Tokyo

Committee Announcements (optional)

None

Table 1 Meeting Attendees

Italics indicates virtual participants

Co-Chairs: Takayuki Nishimura (SCREEN Semiconductor Solutions), Mitsuhiko Matsuda (Hitachi Kokusai Electric)

SEMI Staff: Chie Yanagisawa

Attendee: 10 + **SEMI:** 1

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Canon Anelva	Sato	Mitsugu	Tokyo Electron	Asakawa	Terry
Hitachi Kokusai Electric	Matsuda	Mitsuhiko	Tokyo Electron	Mochizuki	Tadashi
Pionics	Somei	Tadashi	Tokyo Electron	Murata	Naoko
Reno Sub-Systems	Hideaki	Ogihara	Self	Sakamoto	Mitch
SCREEN Semiconductor Solutions	Nishimura	Takayuki			
SCREEN Semiconductor Solutions	Takasaki	Yoshihisa	SEMI Japan	Yanagisawa	Chie

** Alphabetical order by company name*

Table 2 Leadership Changes

<i>Group</i>	<i>Previous Leader</i>	<i>New Leader</i>
GEM300 Task Force	Yoshihisa Takasaki (SCREEN Semiconductor Solutions)	Yoshihisa Takasaki (SCREEN Semiconductor Solutions) Yuko Toyoshima (Hitachi High-Technologies)

*This information was on the CER for December 5, 2015, but no record exists in the meeting minutes. TF leaders were reconfirmed at the TC Chapter meeting on April 23, 2015.

Table 3 Ballot Results (or move to Section 4, Ballot Review)

Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5828	Line-item Revision to: SEMI E170-0215: SPECIFICATION FOR PRODUCTION RECIPE CACHE (PRC) and SEMI E170.1-0215: SPECIFICATION FOR SECS-II PROTOCOL FOR PRODCUTION RECIPE CACHE	/
Line Item 1	Introduce Secured Recipe Space and revise messages	Passed as balloted
Line Item 2	Expression improvements	Passed as balloted Superclean

Table 3 Ballot Results (or move to Section 4, Ballot Review)

Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

Document #	Document Title	Committee Action
Line Item 3	Clarify MaxNumber and MaxTime	Passed as balloted Superclean
Line Item 4	Change APPENDIX 1 to related information	Passed as balloted Superclean

Table 4 Authorized Ballots (or move to Section 7, New Business)

#	When	SC/TF/WG	Details
5601A	Cycle 5 through Cycle 7	GEM300 TF	New Standard: Specification for Wafer Object Model
5829	Cycle 5 through Cycle 7	GEM300 TF	Line Item Revision to SEMI E171-mmyy: Specification for Predictive Carrier Logistics (PCL) (SEMI Doc. 5735) and SEMI E171.1-mmyy: Specification for SECS-II Protocol for Predictive Carrier Logistics (PCL) (SEMI Doc. 5778)

Table 5 Authorized Activities (or move to Section 7, New Business)

#	Type	SC/TF/WG	Details
TBD*	SNARF	GEM300 TF	Revision to SEMI E170-mm15 (SEMI Doc. #5828): SPECIFICATION FOR PRODUCTION RECIPE CACHE (PRC) and SEMI E170.1-mm15 (SEMI Doc. #5828): SPECIFICATION FOR SECS-II PROTOCOL FOR PRODUCTION RECIPE CACHE <i>To be submitted for GCS approval after two-weeks I&C Global Technical Committee Member Review.</i>

Table 6 New Action Items (or move to Section 8, Action Item Review)

Item #	Assigned to	Details
20150423-#1	EISS TF	To discuss future activity to report at the next Japan TC Chapter meeting
20150423-#2	SEMI Staff	To ask to SEMI Publication staff to publish Doc. 5753 (Revision to SEMI E171) and Doc. 5778 (New subordinate document to SEMI E171)
20150423-#3	SEMI Staff	To provide Japan TC chapter with information of the documents which passed after their publication for four years
20150423-#4	The Japan TC Chapter co-chairs	To get approval of this charter change from GCS and propose to RSC to get approval from ISC as following. <i>“To explore, evaluate, discuss, and formulate consensus based specifications that, through voluntary compliance, will enhance the manufacturing capability of the semiconductor industry. Its scope is limited to exploring and developing standards that pertain to the interface and functions of manufacturing tools to each other, to control computers, or to human operators, for the purpose of transferring commands and data used during the manufacturing process.”</i>

Table 7 Previous Meeting Actions Items (or move to Section 8, Action item Review)

Item #	Assigned to	Details
20141205-#4	Mitsuhiro Matsuda (Hitachi Kokusai Electric)	To contact to Lance Rist (NA WTW TF leader) about the liaison with PCL activity => OPEN

1 Welcome, Reminders, and Introductions

Takayuki Nishimura (SCREEN Semiconductor Solutions) called the meeting to order at 1:30 p.m. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on December 5, 2014.

Motion:	To approve the minutes of the previous meeting with editorial changes
By / 2nd:	Mitsuhiro Matsuda (Hitachi Kokusai Electric) / Yoshihisa Takasaki (SCREEN Semiconductor Solutions)
Discussion:	None
Vote:	8 in favor and 0 opposed. Motion Passed.

3 Liaison Reports

3.1 Europe

No report was provided for the Europe TC Chapter.

3.2 Korea

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Korea TC Chapter as attached.

Attachment: [01_KR_I&C_liaison_20150327](#)

3.3 North America

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the North America TC Chapter as attached.

Attachment: [02_NA I&C report April 2015_0.1](#)

3.4 Taiwan

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the Taiwan TC Chapter as attached.

Attachment: [03_Taiwan I&C Standard Committee Liaison Report March 2015](#)

3.5 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) reported for the SEMI Staff Report as attached. Of note:

- Global SEMI Events
- Global Standards Meetings Schedule
- Ballot Critical Dates
- New Regulations and Procedure Guide
- Publication Update

Attachment: [04_SEMI Staff Report 2015 April R0.4a, 05_Regs_SC_to_JRSC2015_0416_rev0.2](#)

The following statement from SEMI Legal Counsel was read to the committee at the NA I&C Committee Spring 2015 meeting:

- *“On February 25, 2015, SEMI filed a complaint for declaratory relief against the PEER Group Inc. (“PEER”) arising from PEER’s assertion of a copyright and trademark in SML and its request for attribution and other license restrictions. We are seeking a judicial determination and order declaring that any member of the public, including SEMI, has the right in the United States to copy the expression embodied in SML, to create and exploit derivative works incorporating SML, and to use “SML” without infringing any right of PEER under*

copyright or trademark law. [SEMI expects that it will take some time before the Court resolves the complaint, and in the meantime, all committee activity related to SML and SML notation is being postponed].”

4 Ballot Review

There was a ballot reviewed at this meeting and the committee actions for each document and each line item are listed in the Table 3 Ballot Results. The details of ballot review are found in the attachments.

Attachment: [06_5828_LineItemLetterBallotReviewSheet_for_ProceduralReview_Final](#)

5 Subcommittee & Task Force Reports

5.1 Equipment Information System Security (EISS) Task Force

Mitch Sakamoto (Self) reported for Equipment Information System Security (EISS) Task Force that there was no activity.

Action Item 1: EISS TF to discuss future activity to report at the next TC Chapter meeting

5.2 Fiducial Mark Interoperability Task Force

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for Fiducial Mark Interoperability Task Force as attached.

Attachment: [07_20150413FMI-TF-Report_r0](#)

5.3 Japan GEM300 Task Force

Yoshihisa Takasaki (SCREEN Semiconductor Solutions) reported for Japan GEM300 Task Force as attached. This report contained information on the following items.

- One document was submitted to Cycle 3
 - #5828 Line Item revisions to E170-0215 (PRC) and E170.1-0215 (PRC SECS-II Mapping)
- New SNARF Proposal
 - Revision to SEMI E170
- Ballot submission proposal
 - #5601: New Standard (WOMS) for Cycle 5 through 7
 - #5829: Revision to E171 (PCL) for Cycle 5 through 7
 - Revision to SEMI E170 and E170.1 (Ballot #5828) for Cycle 6 through 8

Attachment: [08_JA_GEM300TF Report_20150423_R3](#)

Terry Asakawa mentioned Ballot #5735 and Ballot #5778 passed A&R in February but those proofs had not been provided to him yet. The Japan TC Chapter of I&C Global Technical Committee has been concerned about the delay of publication because a task force had to wait to propose a ballot submission for revision until the document would be published.

Action Item 2: SEMI Staff to ask to SEMI Publication staff to publish Doc. 5753 (Revision to SEMI E171) and Doc. 5778 (New subordinate document to SEMI E171)

5.4 Japan I&C Maintenance Task Force

Mitsuhiro Matsuda reported for Japan I&C Maintenance Task Force as attached. Of note:

- #5615: Revision to SEMI E98-0309
- 5 Year Review documents
 - SEMI E153-0310
 - SEMI E99-1104E (Reapproved 0710)
 - SEMI E107-1102 (Reapproved 0710)

Attachment: 09_20150423JPMaintenanceTF-Report_r0

5.5 Sensor Bus Task Force

Hideaki Ogihara (Reno Sub-Systems) commented that the task force would like to revise their documents in order to harmonize them with the SEMI E54.22-0914.

6 Old Business

6.1 The Previous Action Items

6.1.1 20141205-#1: Mitsuhiro Matsuda (Hitachi Kokusai Electric): To ask if NA DDA TF the wording “EDA freeze versions” is proper in this context in NA liaison report. => No need to ask it because Doc. #5762 passed => CLOSE

6.1.2 20141205-#4: Mitsuhiro Matsuda (Hitachi Kokusai Electric): To contact to Lance Rist (NA WTW TF leader) about the liaison with PCL activity => OPEN

6.2 Japan GEM300 TF Leader

This information was on the CER for December 5, 2015, but no record exists in the meeting minutes. TF leaders were reconfirmed at the TC Chapter meeting on April 23, 2015.

Motion:	To approve Yuko Toyoshima (Hitachi High-Technologies) as Japan GEM300 TF co-leader
By / 2nd:	Mitsuhiro Matsuda (Hitachi Kokusai Electric) / Yoshihisa Takasaki (SCREEN Semiconductor Solutions)
Discussion:	None
Vote:	8 in favor and 0 opposed. Motion passed.

7 New Business

7.1 Comments from A&R members for Ballot 5731

There were comments from A&R members for Ballot 5731 as following.

- Lori Nye: Encourage the I&C Committee to address concerns raised in ballots 5731 and 5735 as new business.
- Mitsune Sakamoto: About the issue of Table 4 in 5731, that was discussed in the negative to 5735, the issue form the voter should be discussed in the 5731.

Yoshihisa Takasaki, co-leader, stated that the negative was already addressed by Japan GEM300 TF, and reflected to Ballot #5828..

7.2 SNARF Proposal

7.2.1 Line Item Revision to SEMI E170 (Ballot #5828)

Terry Asakawa addressed the committee on this topic.

Motion:	To approve the SNARF “Revision to SEMI E170-mm15 (SEMI Doc. #5828): SPECIFICATION FOR PRODUCTION RECIPE CACHE (PRC) and SEMI E170.1-mm15 (SEMI Doc. #5828): SPECIFICATION FOR SECS-II PROTOCOL FOR PRODUCTION RECIPE CACHE”
By / 2nd:	Terry Asakawa (Tokyo Electron) / Yoshihisa Takasaki (SCREEN Semiconductor Solutions)
Discussion:	None
Vote:	8 in favor and 0 opposed. Motion passed.

The proposed SNARF will be submitted for GCS approval after two weeks I&C Global Technical Committee Member Review per Procedure Manual 2.2.7.3.

7.3 Ballot Submission Proposal

7.3.1 #5601A: New Standard: Specification for Wafer Object Model (WOMS)

Yoshihisa Takasaki addressed the committee on this topic.

Motion:	To approve to submit the ballot #5601A: New Standard: Specification for Wafer Object Model (WOMS) for Cycle 5 through Cycle 7
By / 2nd:	Yoshihisa Takasaki (SCREEN Semiconductor Solutions) / Naoko Murata (Tokyo Electron)
Discussion:	None
Vote:	8 in favor and 0 opposed. Motion passed.

7.3.2 #5829 Line Item Revision to SEMI E171 and E171.1

Terry Asakawa addressed the committee on this topic.

Motion:	To approve to submit the ballot #5829: Line Item Revision to SEMI E171-mmyy: Specification for Predictive Carrier Logistics (PCL) (SEMI Doc. 5735) and SEMI E171.1-mmyy: Specification for SECS-II Protocol for Predictive Carrier Logistics (PCL) (SEMI Doc. 5778) for Cycle 5 through Cycle 7
By / 2nd:	Yoshihisa Takasaki (SCREEN Semiconductor Solutions) / Naoko Murata (Tokyo Electron)
Discussion:	None
Vote:	8 in favor and 0 opposed. Motion passed.

7.3.3 #XXXX Line Item Revision to SEMI E170 and E170.1 (Ballot #5828)

Terry Asakawa addressed the committee on this topic.

Motion:	To approve to submit the ballot #XXXX: Revision to SEMI E170-mm15 (SEMI Doc. #5828): SPECIFICATION FOR PRODUCTION RECIPE CACHE (PRC) and SEMI E170.1-mm15 (SEMI Doc. #5828): SPECIFICATION FOR SECS-II PROTOCOL FOR PRODUCTION RECIPE CACHE for Cycle 6 through Cycle 8
By / 2nd:	Yoshihisa Takasaki (SCREEN Semiconductor Solutions) / Naoko Murata (Tokyo Electron)
Discussion:	None
Vote:	8 in favor and 0 opposed. Motion passed.

The motion passed, but Japan TC Chapter co-chairs determined this approval is invalid because ballot submission shall be approved after SNARF is approved. This motion may approve on the next TC Chapter meeting.

7.4 5 Year Review Check

The Japan TC Chapter confirmed that there was no document to be reviewed this time.

Action Item 3: SEMI Staff to provide Japan TC Chapter with information of the documents which passed for four years after their publications

7.5 SNARF Project Period Check

The Japan TC Chapter confirmed that there was no SNARF which passed for three years this time after the approval.

7.6 I&C Global Technical Committee Charter Review

The Japan TC Chapter reviewed the current charter of I&C Global Technical Committee and decided to make a proposal for revision as following.

Motion:	The Japan TC Chapter co-chairs to get approval of this charter change from GCS and propose to RSC to get approval from ISC.
By / 2nd:	Mitsuhiro Matsuda (Hitachi Kokusai Electric) / Terry Asakawa (Tokyo Electron)
Discussion:	<p>Here is the current charter.</p> <p><i>“To explore, evaluate, discuss, and formulate consensus based specifications that, through voluntary compliance, will enhance the manufacturing capability of the semiconductor industry. Its scope is limited to exploring and developing standards that pertain to the interface <u>and functions</u> of manufacturing tools to each other, to control computers, or to human operators, <u>for the purpose of transferring commands and data used during the manufacturing process.</u>”</i></p> <ol style="list-style-type: none"> 1. It would be proper without the phrase <u>“and functions”</u>, because the word “interface” with <u>“and functions”</u> looks in a narrow sense. So, the phrase <u>“and functions”</u> should be deleted. 2. The phrase <u>“for the purpose of transferring commands and data used during the manufacturing process”</u> looks

	too detailed. So, the phrase should be deleted.
Vote:	7 in favor and 0 opposed. Motion passed.

Action Item 4: The Japan TC Chapter co-chair to get approval of this charter change from GCS and propose to RSC to get approval from ISC as following.

“To explore, evaluate, discuss, and formulate consensus based specifications that, through voluntary compliance, will enhance the manufacturing capability of the semiconductor industry. Its scope is limited to exploring and developing standards that pertain to the interface ~~and functions~~ of manufacturing tools to each other, to control computers, or to human operators, ~~for the purpose of transferring commands and data used during the manufacturing process.~~”

7.7 Auxiliary Doc for DDA TF

North America DDA Task Force assigned to Mitsuhiro Matsuda (Hitachi Kokusai Electric) to develop a draft of an auxiliary document for defining the freeze version of EDA. He asked if anyone could voluntarily cooperate with him on making a draft document in Japan region. He also commented he would prepare the draft and ask for review it at the next Japan TC Chapter meeting in June.

8 Action Item Review

8.1 Open Action Items

Chie Yanagisawa (SEMI Japan) reviewed the open action item. This can be found in the Previous Meeting Action Items table at the beginning of these minutes.

8.2 New Action Items

Chie Yanagisawa reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

9 Next Meeting and Adjournment

The next meeting of the Japan TC Chapter of Information & Control Global Technical Committee was tentatively scheduled for Tuesday, June 23, 2015 at Japan Standards Summer 2015 Meetings in Tokyo at this meeting.

The fixed meeting schedule was announced as it would be held on Tuesday, June 30, 2015 at a later date.

Respectfully submitted by:
 Chie Yanagisawa
 Senior Standard Coordinator
 SEMI Japan
 Phone: +81.3.3222.5863
 Email: cyanagisawa@semi.org

Minutes approved by:

Takayuki Nishimura (SCREEN Semiconductor Solutions), Co-chair	June 26, 2015
Mitsuhiro Matsuda (Hitachi Kokusai Electric), Co-chair	June 26, 2015

Table 8 Index of Available Attachments #1

#	Title	#	Title
01	KR_I&C_liaison_20150327	06	5828_LineItemLetterBallotReviewSheet_for_ProceduralReview_Final
02	NA I&C report April 2015_0.1	07	20150413FMI-TF-Report_r0
03	Taiwan I&C Standard Committee Liaison Report March 2015	08	JA_GEM300TF Report_20150423_R3
04	SEMI Staff Report 2015 April R0.4a	09	20150423JPMaintenanceTF-Report_r0
05	Regs_SC_to_JRSC2015_0416_rev0.2		

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.